

PO2071

## FLEXIBLE HARD Ti-BASED NITRIDES FILMS WITH ENHANCED RESISTANCE TO CRACKING

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The paper reports on the texture (preferred orientation) and mechanical properties of magnetron sputtered  $\text{Ti}(\text{Ni})\text{N}_x$  and  $\text{Ti}(\text{Al},\text{V})\text{N}_x$  films and their resistance to cracking in bending. The films were reactively sputtered on Si(111) plate and Mo strips in a mixture of Ar+N<sub>2</sub> gases using a DC magnetron equipped with a TiAlV alloy target (6 at.% Al, 4 at. % V), or a TiNi alloy target (5 at.% Ni) respectively. The preferred orientation, structure, macrostress, mechanical properties (the hardness H, effective Young's modulus  $E^*$ , elastic recovery  $W_e$ ), of  $\text{Ti}(\text{Ni})\text{N}_x$  and  $\text{Ti}(\text{Al},\text{V})\text{N}_x$  films and their resistance to cracking in bending were characterized by (i) the X-ray diffraction (XRD), (ii) Scanning Electron Microscope (SEM), (iii) the bending of Si(111) plate using the Stoney's formula, (iv) the diamond indentation test and (v) the bending of coated Mo strip around a fixed cylinder of small radius (down to 5 mm), respectively. It was found that: (1) the preferred orientation of sputtered  $\text{Ti}(\text{Ni})\text{N}_x$  and  $\text{Ti}(\text{Al},\text{V})\text{N}_x$  nitride films depends on energy  $E_{bi} \approx U_s \times i_s / a_D$  delivered to the film during its growth, here is  $U_s$  the substrate bias,  $i_s$  is the substrate current density and  $a_D$  the deposition rate. The texture continuously changes from (i)  $\text{TiN}(220) \rightarrow \text{TiN}(111) + \text{TiN}(200) \rightarrow \text{TiN}(220)$  for  $\text{Ti}(\text{Ni})\text{N}_x$  films and (ii)  $\text{TiN}(200) \rightarrow \text{TiN}(220) \rightarrow \text{TiN}(111) + \text{TiN}(220)$  for  $\text{Ti}(\text{Al},\text{V})\text{N}_x$  nitride films with increasing  $E_{bi}$ . (2) The  $\text{Ti}(\text{Al},\text{V})\text{N}_x$  and  $\text{Ti}(\text{Ni})\text{N}_x$  nitride films with low resistance to cracking are prepared at lower value of  $E_{bi} < 1.5 \text{ MJ/cm}^3$  and exhibit (i) low ratio  $H/E^* \leq 0.1$ , low elastic recovery  $W_e \leq 65\%$ , compressive macrostress ( $\sigma < 0 \text{ GPa}$ ) and (ii) are composed of grains contain  $\text{TiN}(200)$  and show a columnar structure. (3) Both the  $\text{Ti}(\text{Al},\text{V})\text{N}_x$  and  $\text{Ti}(\text{Ni})\text{N}_x$  nitride films with enhanced resistance to cracking are prepared at higher value of  $E_{bi} > 3.7 \text{ MJ/cm}^3$  and exhibit (i) high ratio  $H/E^* > 0.1$ , high elastic recovery  $W_e > 65\%$ , compressive macrostress ( $\sigma < 0 \text{ GPa}$ ) and (ii) are composed of grains which do not contain  $\text{TiN}(200)$  and show a dense (voids free) structure.

### Keywords

Multifunctional coatings  
Resistance to cracking  
Mechanical properties  
Magnetron sputtering  
Ion bombardment